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PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Yasuo Kobayashi, et al.

International Application No.: PCT/JP2004/004070

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U.S. Serial No.: To Be Assigned

Group Art Unit: To Be Assigned

Filed: : Herewith

Examiner: To Be Assigned

For: PLASMA-ASSISTED DEPOSITION METHOD AND
PLASMA-ASSISTED DEPOSITION SYSTEM

PRELIMINARY AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Prior to or concurrent with calculation of the filing fees, please further amend
this application, as amended previously (twice) under Article 34, as follows.